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INDEX, VOLUME 29

CONTENTS

March 1968

	PAGE
A Solid-State Low-Noise Preamplifier and Picture-Tube Drive Amplifier for a 60-MHz Video System	3
O. H. SCHADE, SR.	
The Si-SiO ₂ Solid-Solid Interface System	22
A. G. REVESZ AND K. H. ZAININGER	
Multipath Problems in Communications between Low-Altitude Spacecraft and Stationary Satellites	77
S. H. DURRANI AND H. STARAS	
Probability Distribution of Time to Phase Lock for a Second-Order Phased-Locked Loop	106
F. S. KEBLAWI	
Quadrature Detection PSK System and Interference	122
V. F. VOLERTAS	
RCA Technical Papers	141
Authors	144

June 1968

R-F Sputtering Process	149
J. L. VOSSEN AND J. J. O'NEILL, JR.	
Laminated-Ferrite Memories—Review and Evaluation	180
R. SHAHBENDER	
An MOS-Transistor-Driven Laminated-Ferrite Memory	199
I. GORDON, R. L. HARVEY, H. I. MOSS, A. D. ROSSI, J. W. TUSKA, J. T. WALLMARK, AND C. WENTWORTH	

High-Power Frequency Doublers Using Coupled TEM Lines	230
C. SUN	
Multiple-Loop Frequency-Compressive Feedback for Angle-Modulation Detection	252
H. HEINEMANN, A. NEWTON, AND J. FRANKLE	
Double-Stream Interaction in a Thin Semiconductor Layer	270
B. B. ROBINSON AND B. VURAL	
Manipulation of Sculptured Surfaces	281
E. P. HELPERT	
Multispectral Vidicon Camera Study	287
J. J. DISHLER AND D. F. LONGCOY	
RCA Technical Papers	298
Authors	301

September 1968

MOS Field-Effect Transistor Drivers for Laminated-Ferrite Memories	311
W. A. BÖSENBERG, D. FLATLEY, AND J. T. WALLMARK	
Development of a 64-Output MOS Transistor Selection Tree	324
J. T. GRABOWSKI	
Monolithic Sense Amplifier for Laminated-Ferrite Memories	355
H. R. BEELITZ	
An Experimental Pulsed CdS Laser Cathode-Ray Tube	379
F. H. NICOLL	
Electromagnetic Wave Propagation in Superconductors	386
P. BURA	
Selection Diversity with Non-Zero Correlations	401
A. SCHMIDT	
Adaptive Detection Mode with Threshold Control as a Function of Spatially Sampled Clutter-Level Estimates	414
H. M. FINN AND R.S. JOHNSON	
RCA Technical Papers	465
Authors	468

December 1968

New Process Technologies for Microelectronics—Foreword	473
J. A. AMICK AND N. E. WOLFF	
Isolation Techniques for Fabricating Integrated Circuits	
I. Laminate Substrates	475
J. A. AMICK AND A. W. FISHER	
II. Dielectric Refill Techniques and Decal Air Isolation	485
A. I. STOLLER AND W. H. SCHILP, JR.	
Relationship Between the Performance of a Linear Amplifier Microcircuit and the Isolation Technique Used in Its Construction ...	507
A. I. STOLLER	
Apparatus for Chemical Vapor Deposition of Oxide and Glass Films ..	525
WERNER KERN	

INDEX

651

Diffusion Characteristics and Applications of Doped Silicon Dioxide Layers Deposited from Silane (SiH_4)	533
A. W. FISHER, J. A. AMICK, H. HYMAN, and J. H. SCOTT, JR.	
Diffusion Characteristics of Doped Silicon Dioxide Layers Deposited from Premixed Hydrides	549
A. W. FISHER and J. A. AMICK	
A Technique for Measuring Etch Rates of Dielectric Films	557
WERNER KERN	
DC Sputtering with RF-Induced Substrate Bias	566
J. L. VOSSEN and J. J. O'NEILL, JR.	
Additive Processing Techniques for Printed-Circuit Boards	582
R. J. RYAN, T. E. MCCURDY, and N. E. WOLFF	
Calculation of the Electrical Parameters of Transistor Chips from Measurements Made on Packaged Units	600
A. I. STOLLER	
Controlled Oxidation of Silane	618
K. STRATER	
Development of P-Channel Enhancement MOS Triodes	630
P. DELIVORIAS	

AUTHORS INDEX, VOLUME 29

	ISSUE	PAGE
Amick, J. A. (Coauthor)—"Isolation Techniques for Fabricating Integrated Circuits I. Laminate Substrates" ...	Dec.	475
(Coauthor)—"Diffusion Characteristics and Applications of Doped Silicon Dioxide Layers Deposited from Silane (SiH_4)"	Dec.	533
(Coauthor)—"Diffusion Characteristics of Doped Silicon Dioxide Layers Deposited from Premixed Hydrides"	Dec.	549
Beelitz, H. R.—"Monolithic Sense Amplifier for Laminated-Ferrite Memories"	Sept.	355
Bösenberg, W. A. (Coauthor)—"MOS Field-Effect Transistor Drivers for Laminated-Ferrite Memories"	Sept.	311
Bura, P.—"Electromagnetic Wave Propagation in Superconductors"	Sept.	386
Delivorias, P.—"Development of P-Channel Enhancement MOS Triodes"	Dec.	630
Dishler, J. J. (Coauthor)—"Multispectral Vidicon Camera Study"	June	287
Durrani, S. H. (Coauthor)—"Multipath Problems in Communications between Low-Altitude Spacecraft and Stationary Satellites"	Mar.	77
Finn, H. M. (Coauthor)—"Adaptive Detection Mode with Threshold Control as a Function of Spatially Sampled Clutter-Level Estimates"	Sept.	414
Fisher, A. W. (Coauthor)—"Isolation Techniques for Fabricating Integrated Circuits I. Laminate Substrates" ...	Dec.	475
(Coauthor)—"Diffusion Characteristics and Applications of Doped Silicon Dioxide Layers Deposited from Silane (SiH_4)"	Dec.	533
(Coauthor)—"Diffusion Characteristics of Doped Silicon Dioxide Layers Deposited from Premixed Hydrides"	Dec.	549
Flatley, D. (Coauthor)—"MOS Field-Effect Transistor Drivers for Laminated-Ferrite Memories"	Sept.	311

Frankle, J. (Coauthor)—"Multiple-Loop Frequency-Compressive Feedback for Angle-Modulation Detection"	June	252
Gordon, I. (Coauthor)—"An MOS-Transistor-Driven Laminated-Ferrite Memory"	June	199
Grabowski, J. T.—"Development of a 64-Output MOS Transistor Selection Tree"	Sept.	324
Harvey, R. L. (Coauthor)—"An MOS-Transistor-Driven Laminated-Ferrite Memory"	June	199
Heinemann, H. (Coauthor)—"Multiple-Loop Frequency-Compressive Feedback for Angle-Modulation Detection" ..	June	252
Helpert, E. P.—"Manipulation of Sculptured Surfaces"	June	281
Hyman, H. (Coauthor)—"Diffusion Characteristics and Applications of Doped Silicon Dioxide Layers Deposited from Silane (SiH ₄)"	Dec.	533
Johnson, R. S. (Coauthor)—"Adaptive Detection Mode with Threshold Control as a Function of Spatially Sampled Clutter-Level Estimates"	Sept.	414
Keblawi, F. S.—"Probability Distribution of Time to Phase Lock for a Second-Order Phased-Locked Loop"	Mar.	106
Kern, W.—"Apparatus for Chemical Vapor Deposition of Oxide and Glass Films"	Dec.	525
—"A Technique for Measuring Etch Rates of Dielectric Films"	Dec.	557
Longcoy, D. F. (Coauthor)—"Multispectral Vidicon Camera Study"	June	287
McCurdy, T. E. (Coauthor)—"Additive Processing Techniques for Printed-Circuit Boards"	Dec.	582
Moss, H. I. (Coauthor)—"An MOS-Transistor-Driven Laminated-Ferrite Memory"	June	199
Newton, A. (Coauthor)—"Multiple-Loop Frequency-Compressive Feedback for Angle-Modulation Detection"	June	252
Nicoll, F. H.—"An Experimental Pulsed CdS Laser Cathode-Ray Tube"	Sept.	379
O'Neill, J. J., Jr. (Coauthor)—"R-F Sputtering Processes" ..	June	149
(Coauthor)—"DC Sputtering with RF-Induced Substrate Bias"	Dec.	566
Revesz, A. G. (Coauthor)—"The Si-SiO ₂ Solid—Solid Interface System"	Mar.	22
Robbi, A. D. (Coauthor)—"An MOS-Transistor-Driven Laminated-Ferrite Memory"	June	199
Robinson, B. B. (Coauthor)—"Double-Stream Interaction in a Thin Semiconductor Layer"	June	270
Ryan, R. J. (Coauthor)—"Additive Processing Techniques for Printed-Circuit Boards"	Dec.	582
Schade, O. H., Sr.—"A Solid-State Low-Noise Preamplifier and Picture Tube Drive Amplifier for a 60-MHz Video System"	Mar.	3
Schilp, W. H., Jr. (Coauthor)—"Isolation Techniques for Fabricating Integrated Circuits II. Dielectric Refill Techniques and Decal Air Isolation"	Dec.	485
Schmidt, A.—"Selection Diversity with Non-Zero Correlations"	Sept.	401
Scott, J. H., Jr. (Coauthor)—"Diffusion Characteristics and Applications of Doped Silicon Dioxide Layers Deposited from Silane (SiH ₄)"	Dec.	533
Shahbender, R.—"Laminated-Ferrite Memories—Review and Evaluation"	June	180
Staras, H. (Coauthor)—"Multipath Problems in Communications between Low-Altitude Spacecraft and Stationary Satellites"	Mar.	77
Stoller, A. I. (Coauthor)—"Isolation Techniques for Fabricating Integrated Circuits II. Dielectric Refill Techniques and Decal Air Isolation"	Dec.	485

—“Relationship Between the Performance of a Linear Amplifier Microcircuit and the Isolation Technique Used in Its Construction”	Dec.	507
—“Calculation of the Electrical Parameters of Transistor Chips from Measurements made on Packaged Units”	Dec.	600
Strater, K.—“Controlled Oxidation of Silane”	Dec.	618
Sun, C.—“High-Power Frequency Doublers Using Coupled TEM Lines”	June	230
Tuska, J. W. (Coauthor)—“An MOS-Transistor-Driven Laminated-Ferrite Memory”	June	199
Volertas, V. F.—“Quadrature Detection PSK System and Interference”	Mar.	122
Vossen, J. L. (Coauthor)—“R-F Sputtering Processes”	June	149
(Coauthor)—“DC Sputtering with RF-Induced Substrate Bias”	Dec.	566
Vural, B. (Coauthor)—“Double-Stream Interaction in a Thin Semiconductor Layer”	June	270
Wallmark, J. T. (Coauthor)—“An MOS-Transistor-Driven Laminated-Ferrite Memory”	June	199
(Coauthor)—“MOS Field-Effect Transistor Drivers for Laminated-Ferrite Memories”	Sept.	311
Wentworth, C. (Coauthor)—“An MOS-Transistor-Driven Laminated-Ferrite Memory”	June	199
Wolff, N. E. (Coauthor)—“Additive Processing Techniques for Printed-Circuit Boards”	Dec.	582
Zaininger K. H. (Coauthor)—“The Si-SiO ₂ Solid-Solid Interface System”	Mar.	22